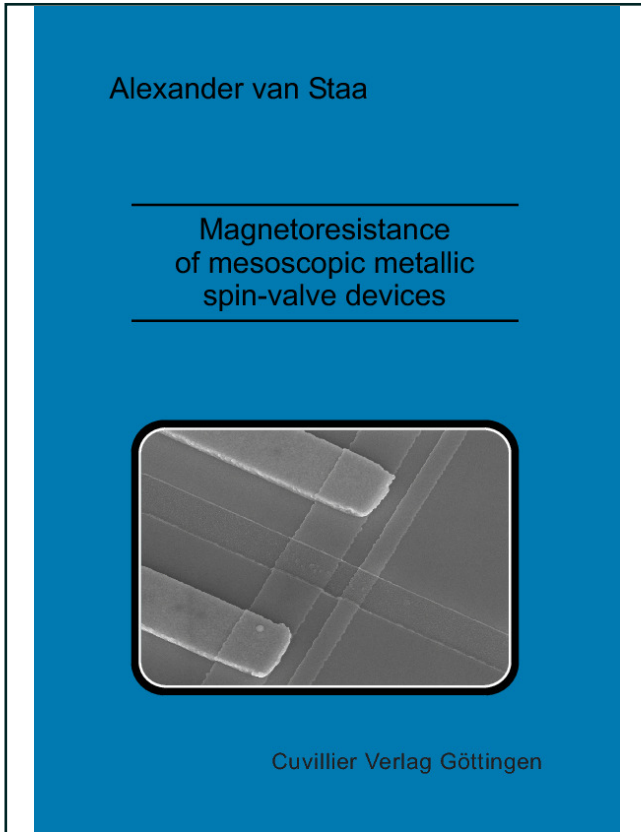




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Magnetoresistance of mesoscopic metallic spin-valve devices



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